



We locate and provide the fab equipment you require

Fab-Finder, Inc.

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>>> 200mm Equipment List <<<

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Item	FF #	Module	Type	Model	Maker	Vintage	Serial Number
1	5	Ash	ILD ASHER	TCA-3822	TOK	199408	T-9405289
2	19	CMP	POLISHER	STRB-6DS	STRASBAUGH	199806	2191097
3	20	CMP	POLISHER	STRB-6DS(SIO)	STRASBAUGH	199804	2100897
4	41	Diff	Vertical Diffusion	α-808SD	TEL	199710	A00009765381
5	42	Diff	Vertical Diffusion	α-808SD	TEL	199710	A00009765380
6	43	Diff	SOG-CURE-FURNACE	α-808SD	TEL	199806	A000097X5544
7	44	Diff	VERTICAL CVD FURNACE	α-808SC	TEL	199505	A00009510004
8	45	Diff	VERTICAL CVD FURNACE	α-808SC	TEL	199408	A00009430005
9	46	Diff	VERTICAL DIFF FURNACE	α-808SD	TEL	199408	A00009430012
10	48	Diff	VERTICAL DIFF FURNACE	α-808SD	TEL	199505	A00009510002
11	49	Diff	VERTICAL DIFF FURNACE	α-808SD	TEL	199509	A00009540062
12	51	Diff	VERTICAL DIFF FURNACE	α-808SD(WOX)	TEL	199705	A00009660293
13	70	Etch	Etcher	CENTURA-MXP	AMAT	200012	29805
14	72	Etch	Metal Etcher	TCP9600SE	Lam Research	200210	42138
15	73	Etch	Metal Etcher	TCP9600-SE	Lam Research	200207	42137
16	74	Etch	DRY ETCHER nit	TE-8401	TEL	200003	K84839
17	75	Etch	DRY ETCHER nit	TE-8401	TEL	200004	K84838
18	76	Etch	DRY ETCHER nit	TE-8401	TEL	200009	K84849
19	77	Etch	DRY ETCHER nit	TE-8401	TEL	200209	K84869
20	78	Etch	DRY ETCHER nit	TE-8401	TEL	200209	K84874
21	79	Etch	SILICON OXIDE ETCHER	TE-8500	TEL	199409	K85159
22	80	Etch	SILICON OXIDE ETCHER	TE-8500	TEL	199409	K85158
23	81	Etch	W ETCHBACK ETCHER	TE-8600	TEL	199604	K86552
24	83	implant	Ion Implanter	XR80	AMAT	199806	M367
25	84	implant	ION IMPLANTATION	E220	Varian	199408	037100
26	100	Litho	STEPPER	FPA-3000iW	Canon	200010	0063-10iW
27	100a	Litho	STEPPER	FPA-3000iW	Canon	199803	711260
28	101	Litho	STEPPER	FPA-2500i3	Canon	199408	404570i3
29	102	Litho	STEPPER	FPA-2500i3	Canon	199408	404569i3
30	119	Litho	COATER/DEVELOPER	CT MK-8	TEL	199408	MD-814156
31	120	Litho	COATER/DEVELOPER	CT MK-8	TEL	199507	814168
32	127	Metals	LPCVD	MB2-730(DCS)	TEL	200012	MCJ-190
33	145	Metro	SEM	JSM-6340F	JEOL	199710	SM168010-35
34	150	Metro	SEM	S-8820	Hitachi	199602	8327-108820
35	155	Metro	SEM	S-8840	Hitachi	199804	910402
36	156	Metro	SEM	S-8840	Hitachi	199803	910409
37	192	Metro	WAFER INSPECTION	KLA-2112	KLA-Tencor	199603	696
38	193	Metro	WAFER INSPECTION	KLA-2115	KLA-Tencor	199710	1016
39	194	Metro	WAFER INSPECTION	KLA-2115	KLA-Tencor	199710	971
40	198	Metro	OVERLAY MEASUREMENT	KLA-5100	KLA-Tencor	199607	1234
41	200	Metro	Overlay measurement	KLA5200	KLA-Tencor	199710	2074
42	213	Metro	Ellipsometer	FE-4	Rudolph	199505	10616
43	221	Metro	SHEET RESIST	M-GAGE300	KLA-Tencor	199408	0294-0715
44	230	Metro	X-RAY FLUORE	S3630	Rigaku		2W0465
45	342	Metro	SPV3030	SPV3030	SDI	200204	97-050126
46	235	RTP	RTA	LA-W815-AV2.5	DNS	199408	53710-4028
47	260	Test	Parametric Tester	4062F	HP	200304	JP10B00135
48	270	Test	Parametric Tester	S-900	Keithley	199602	QMO 2641
49	271	Test	Parametric Tester	S-900	Keithley	199602	QMO 2640
50	308	Test	Prober	MP-10+SA-60A	MJC	199408	5069405076
51	309	Test	Prober	78S	TEL	199510	7SA2109
52	310	Test	Prober	78S	TEL	199408	7SA0101
53	312	Test	Prober	78S FOR HP4062	TEL	199603	7SA2406
54	324	Test	Spectro-photometer	HP8452A	HP	199411	3104G02964
55	331	Thin Film	SOG+cure SYSTEM	CT MK-8+mini furnace	TEL	199408	MD-814174
56	332	Thin Film	Dep-Etch SYSTEM	P-5000, 2 dep, 1 etch	AMAT	199505	E2262
57	335	Thin Film	SACVD MACHINE	P-5000(BPSG.Co) 2 chbr	AMAT	200204	ER045,P5903
58	337	Thin Film	SACVD MACHINE	P-5000SACVD 3 chbr	AMAT	200405	5629



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Items # 59-73. Special discount pricing tools. Please ask for details							
59	47	Diff	VERTICAL DIFF FURNACE	α-808SD	TEL	199408	A00009430013
60	50	Diff	VERTICAL DIFF FURNACE	α-808SD	TEL	199910	A00009660294
61	151	Metro	SEM	S-8820	Hitachi	199602	8328-018820
62	158	Metro	FIB	SMI-8800SE	SII	199408	089P06-01
63	195	Metro	Wafer Inspection	KLA2118	KLA-Tencor	200007	1235
64	196	Metro	INSPECTION SYSTEM	KLA-2131	KLA-Tencor	199507	593
65	197	Metro	WAFER INSPECTION	KLA-2552	KLA-Tencor	199604	718
66	224	Metro	FILM THICKNESS	P2	KLA-Tencor	199408	4940323
67	269	Test	Parametric Tester	S900A	Keithley	200304	QMO:2630
68	272	Test	Prober	78S S	TEL	199602	7SA2603
69	273	Test	Prober	78S S	TEL	199602	7SA2602
70	306	Test	Prober	EG4080X	Electrogilas	199602	H495120681
71	307	Test	Prober	MP-10	MJC	199408	5069405075
72	311	Test	Prober	78S	TEL	199408	7S0312
73	323	Test	Hot-electron analyzer	C3230-05,MP-10	Hamamatsu Photonics	199411	697208

Part 2

1	2	Thin Film	CVD	CENTURA 5200	AMAT	1997	E-7222
2	3	Thin Film	CVD	CENTURA(3CHB)	AMAT	1999	E-9240
3	4	Thin Film	CVD	CENTURA(3CHB)	AMAT	2000	CA98
4	17	CMP	Polisher	MIRRA-3400(ILD)	AMAT	1999	E-1027/P-9360
5	18	CMP	Polisher	MIRRA-3400(ILD)	AMAT	2000	P-L632/E-12222
6	20	CMP	Polisher	MIRRA-3400(ILD)	AMAT	2000	E30877/P308460
7	21	CMP	Polisher	MIRRA-3400(ILD)	AMAT	2003	MIRRA-SIO
8	22	CMP	Polisher	MIRRA-3400(W)	AMAT	1999	E-9373/P-L493
9	23	CMP	Polisher	MIRRA-3400(W)	AMAT	2000	P302422/E12212
10	24	CMP	Polisher	MIRRA-3400(W)	AMAT	2000	P308446/E30876
11	25	CMP	Polisher	MIRRA-3400(W)	AMAT	2003	E-43708/P-L582
12	28	Metro	Review SEM	SEMVISION_CX	AMAT	2001	W-863
13	29	Litho	Stepper	FPA-3000EX5	Canon	1999	9025032EX5
14	31	Litho	Stepper	FPA-3000EX5	Canon	2000	9115074
15	32	Litho	Stepper	FPA-3000EX5	Canon	2001	115081
16	33	Metro	Resistivity mapping system	RESMAP468	CDE	2006	B07326468
17	34	xBack End	Grinder	DFG-82IF/8	Disco	1990	GG0126
18	35	xBack End	Grinder	DFG-82IF/8	Disco	1991	GG0175
19	38	Wet Clean	Wet Etching Systems	FC-820L	DNS	1997	56630-2008
20	41	Litho	Coater	SC-W80A-AVG	DNS	1995	54700-2808
21	42	Wet Clean	Spin Processor	SP-W813-U	DNS	1997	56530-2539
22	52	Metro	Resistivity mapping system	RS35C	KLA-Tencor	1996	951013
23	53	Metro	Resistivity mapping system	RS35C	KLA-Tencor	1996	960124
24	56	Etch	Etcher	ALLIANCE9100	Lam Research	2000	8788
25	57	Etch	Etcher	ALLIANCE9100	Lam Research	2000	8817
26	58	Ash	Asher	ASPEN2	Mattson	1996	263
27	61	Metro	Microscope	X6PDER-UBD	Nikon	1990	265868
28	62	Metro	Microscope	X6PDER-UBD	Nikon	1990	265233
29	63	Metro	Microscope	X6PDUW-UBD	Nikon	1990	264948
30	64	Metro	Microscope	X6PDUW-UBD	Nikon	1990	
31	65	Metro	Wafer Inspection	OPTISTATION V	Nikon	2006	45412
32	66	Metro	Wafer Inspection	OPTISTATION V	Nikon	2006	45411
33	67	Metro	Wafer Inspection	AL-2100	Olympus	2006	108047
34	73	Metro	FIB	SMI8800	SII	1995	089P0703
35	74	CMP	Polisher	6DS-SP	STRASBAUGH	1997	900895
36	75	CMP	Polisher	6DS-SP	STRASBAUGH	1997	1181295
37	76	CMP	Polisher	6DS-SP	STRASBAUGH	1997	1590596
38	83	Litho	Coater	CT-MK7	TEL	1996	MD-715692
39	84	Litho	Coater	CT-MK7	TEL	1997	MD-7171115
40	89	Metals	LPCVD	MB2-730	TEL	2000	MCJ-181
41	90	Metals	Sputter	MB2-830(TI/C)	TEL	1995	MPJ-09
42	91	Metals	Sputter	MB2-830(TI/TIN)	TEL	1997	MPJ-023
43	92	Metals	Sputter	MB2-830(TIN)	TEL	1996	MPJ-016
44	94	Etch	Dry Etching	TE-8600STRIE	TEL	1996	K86447
45	95	Etch	Oxide Etching	UN85DI	TEL	2000	U01128
46	96	Etch	Oxide Etching	UN85DI	TEL	2000	U01400
47	97	Etch	Oxide Etching	UN85DI	TEL	2000	U00973
48	98	Etch	Oxide Etching	UN85DI	TEL	2000	U01133
49	99	Etch	Etcher	UNITY285DP	TEL	1997	186
50	120	Litho	UV Cure	UMA-1002-HC93FW	Ushio	1996	9511003
51	126	Metro	Resistivity mapping system	RS75TC	KLA-Tencor	1997	970417
52	127	Metro	Wafer Inspection	IS2600	Hitachi	2006	12675
53	128	Diff	Furnace	DJ-853V-8DL HTO	HitachiKokusai		T2DC3-11000-1
54	130	Litho	Coater	SC-W80A-AV	DNS	1995	54700-2811
55	133	Metro	Surface Analyzer	SURFSCAN 7600	KLA-Tencor	1995	0295-494
56	136	Ash	Dry Etcher	ASPEN-2C	Mattson	2005	#55
57	137	Metro	Thin Film Measurement	NANOSPEC 8000XSE	Nanometrics	2000	8000X-0100-0178
58	139	Metro	Thin Film Measurement	NANOSPEC 8000XSE-NT	Nanometrics	2001	L8000X-03010228
59	143	Thin Film	PLASMA CVD SYSTEM	CENTURA(SION)	AMAT	2002	5200-1002